

	Type	Hits	Search Text	DBs
1	BRS	3274	transistor and STI	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
2	BRS	1990	(transistor and STI) and 438/\$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
3	BRS	495	438/296.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
4	BRS	762	438/404.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
5	BRS	984	438/424.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
6	BRS	324	438/690.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
7	BRS	497	438/691.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
8	BRS	3357	438/694.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
9	BRS	302	438/697.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
10	BRS	2265	438/699.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
11	BRS	602	438/700.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
12	BRS	2	6197691.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
13	BRS	1	6197691.URPN.	USPAT
14	BRS	12	("5173439"   "5498565"   "5665202"   "5728621"   "5792707"   "5817567"   "5880007"   "5943590"   "5958795"   "6037018"   "6048775"   "6090714").PN.	USPAT
15	BRS	5	("5929504"   "5943590"   "6197691"   "6225225"   "6287939").PN.	USPAT
16	BRS	868	high adj density adj plasma near chemical adj vapor adj deposition	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
17	BRS	43993	deposition with sputtering	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

	Time Stamp	Comments	Error Definition	Errors
1	2003/04/23 16:57			0
2	2003/04/23 16:59			0
3	2003/04/23 17:05			0
4	2003/04/23 17:05			0
5	2003/04/23 17:05			0
6	2003/04/23 17:05			0
7	2003/04/23 17:05			0
8	2003/04/23 17:05			0
9	2003/04/23 17:05			0
10	2003/04/23 17:05			0
11	2003/04/23 17:05			0
12	2003/05/07 13:02			0
13	2003/05/07 13:02			0
14	2003/05/07 13:03			0
15	2003/05/07 13:04			0
16	2003/05/07 14:16			0
17	2003/05/07 14:17			0

	Type	Hits	Search Text	DBs
18	BRS	70	(high adj density adj plasma near chemical adj vapor adj deposition) same (deposition with sputtering)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB
19	BRS	4	((high adj density adj plasma near chemical adj vapor adj deposition) same (deposition with sputtering)) and sputter adj ratio	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB

	Time Stamp	Comments	Error Definition	Errors
18	2003/05/07 14:17			0
19	2003/05/07 14:22			0